

## INFORMATION DISCLOSURE CITATION

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Applicants	Yukiteru MATSUI et al.			
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U.S. PATENT DOCUMENTS							
Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate	
DVN	6,364,744 B1/	04/02/02	MERCHANT et al.				

FOREIGN PATENT DOCUMENTS							
	Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No	
DVN	2001-308041/	11/02/01	JAPAN			ABSTRACT	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
DVN	MATSUI, Y. et al., "Chemical Mechanical Polishing Slurry Containing Abrasive Particles Exhibiting Photocatalytic Function", Application Serial No. 10/201,488, filed on July 24, 2002.

Examiner	<i>DVN</i>	Date Considered	7-23-2004
*Examiner:	Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.		
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